

REMARKS

The rejections of Claims 1-4 and 7-10 as being unpatentable over Ishii in view of Masuda et al. and Nakajima et al., of Claims 5 and 6 as being unpatentable over the foregoing three documents and further in view of Ye et al., of Claim 11 as being unpatentable over said three documents and further in view of Steger et al., and of Claim 12 as being unpatentable over said three documents and further in view of Otsuki, all under 35 U.S.C. § 103(a), are traversed. Reconsideration of each of these rejections is respectfully requested in light of the above amendments and following comments.

The claimed shield electrode designated by numeral 15 in Fig. 1 surrounds the vacuum reactor. The power source 16 provides a high frequency power that is lower than the power provided by the power source 8 as the power of the latter may be equal to that of the power source 16 (page 9, lines 5-9 and lines 22-24). Thereby, the voltage potential on the outer circumferential wall of the vacuum reactor can be set to a value below the plasma voltage potential, and deposition of the reaction products on the inner wall is prevented (page 11, lines 5-15).

The cited documents relied upon in the Office Action do not, either singly or in combination, teach or even suggest the now claimed shield structure or the result produced thereby. For example, the shield electrode of Nakajima et al. is

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not arranged so as to control the voltage potential of an outer circumferential wall of a vacuum reactor.

Accordingly, early and favorable action is currently solicited. If there are any questions regarding this amendment or the application in general, a telephone call to the undersigned would be appreciated since this should expedite the prosecution of the application for all concerned.

If necessary to effect a timely response, this paper should be considered as a petition for an Extension of Time sufficient to effect a timely response, and please charge any deficiency in fees or credit any overpayments to Deposit Account No. 05-1323 (Docket #056204.53113US).

Respectfully submitted,

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